

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Gurtej S. Sandhu and Sujit Sharan

§ Group Art Unit:

Serial No.:

§ Examiner:

Filed: November 12, 1999

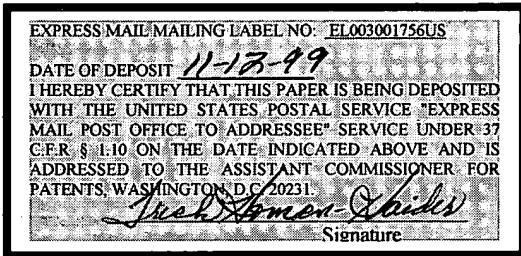
§ Atty. Docket: 95-0392.02

For: METHOD FOR IN-SITU CLEANING OF
INDUCTIVELY-COUPLED PLASMA CHAMBERS

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§

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231



Dear Sir:

After awarding this application the benefit of the filing date of the parent application – serial number 08/795,379 filed February 4, 1997 – please amend the accompanying continuation application as follows:

IN THE DRAWINGS

Applicants note that the drawings submitted as part of this application are not the informal drawings originally submitted as part of the parent application. Rather, they are the formal drawings that were submitted at the end of prosecuting the parent application.

IN THE SPECIFICATION

In the title, please replace “METHOD” with --DEVICE--.